Electronic Version
Stylesheet Version v1.1.1

Claims

[c1] A CVD apparatus comprising:
a vacuum vessel separated into two chambers;
the first one of the two chambers containing a radio-frequency electrode;
the second one of the two chamber containing a substrate support mechanism for mounting a substrate;
wherein said vacuum vessel is separated by an electrically conductive partitioning section, said partitioning section comprising:
a plurality of through-holes to allow communication between the first chamber and the second chamber;
an interior space for receiving a reactive gas, the interior space separated from the first chamber and communicating with the second chamber through a plurality of diffusion holes; and
a heater for heating the electrically conductive partition section.

[c2] The apparatus of claim 1, further comprising:
an electrically conductive spiral shield; and
wherein the partitioning section is mounted to the vacuum vessel by means of a mounting screw such that

electrical contact between the partitioning section and the vacuum vessel is achieved through said spiral shield.

[c3] A CVD apparatus comprising:
a vacuum vessel separated into two chambers;
at least one radio-frequency electrode contained in a first one of said two chambers;
a substrate support mechanism contained in the second one of said two chambers;
an electrically conductive partition section;
an electrically conductive spiral shield; and
wherein said vacuum vessel is separated into two chambers by said electrically conductive partition section which is mounted to said vacuum vessel by means of a mounting screw such that electrical contact between the partitioning section and the vacuum vessel is achieved through said spiral shield.